

**REMARKS**

At the outset, the Examiner is thanked for the thorough review and consideration of the pending application. The office action dated November 14, 2003 has been received, and its contents carefully reviewed.

Claims 5-14 remain in the application with claims 5, 7, 10, 11, and 13 amended and claims 1-4 withdrawn.

In the Office Action, the Examiner objected to claim 13 under 37 CFR 1.75(c) as being in improper dependent form. The Examiner rejected claims 5-14 under 35 U.S.C. § 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention; and claims 5-14 under 35 U.S.C. § 103(a) as being unpatentable over U.S. Patent No. 6,368,954 to Im (hereinafter "Im").

The objection to claim 13 as being in improper dependent form is respectfully traversed and reconsideration is requested. Claims 11 and 13 has been amended to overcome this objection.

The rejection of claim 5-14 under U.S.C. § 112, second paragraph, is respectfully traversed and reconsideration is requested. Claims 5, 10, 11, and 13 have been amended, and Applicant respectfully requests the withdrawal of this rejection.

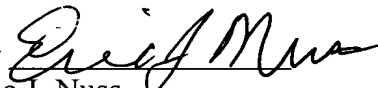
The rejection of claims 5-14 under U.S.C. § 103(a) is respectfully traversed and reconsideration is requested. Claim 5 is allowable over the cited references in that this claim recites a combination of elements including, for example, "moving the mask by several micrometers using the mask stage" and "moving the X-Y stage having the substrate to crystallize another block of the amorphous silicon film". Claim 11 is allowable over the cited references in that this claim recites a combination of elements including, for example, "moving the mask by several micrometers so that the plurality of slits correspond to next portions of the amorphous silicon film that have not been crystallized" and "moving the substrate to correspond to a next block of the amorphous silicon film, the next block having a portion with uncrystallized silicon film". Im does not teach or suggest at least these features of the claimed invention. While Im may teach moving either the masking system 150 or the sample stage 180, it does not teach a method where both are moved as part of the crystallization process. Therefore, claims 5 and 11 and claims 5-10 and 12- 14, which depend therefrom respectively, are allowable over Im.

If for any reason the Examiner finds the application other than in condition for allowance, the Examiner is requested to call the undersigned attorney at (202) 496-7500 to discuss the steps necessary for placing the application in condition for allowance. All correspondence should continue to be sent to the below-listed address.

If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time, or any other fees required to complete the filing of this response, may be charged to Deposit Account No. 50-0911. Please credit any overpayment to deposit Account No. 50-0911. A duplicate copy of this sheet is enclosed.

Dated: January 20, 2004

Respectfully submitted,

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